## AMENDMENTS

## In the Claims:

1-49. (cancelled)

 (currently amended) A process for forming a patterned thin film structure on a substrate, comprising:

printing on the substrate with a printable first material a pattern that defines-the area where the thin film structure is to be formed by comprising a positive image thereof of the thin film structure such that the printable first material is printed in the area where the thin film structure is to be formed, the printable first material being strippable using a first solvent;

overcoating the printed surface of the substrate with a second material that is not strippable using the first solvent;

stripping the first material away using the first solvent in a process that strips away the first material and any portions of the second material formed on the first material without stripping away the portions of the second material formed directly on the substrate, such that the second material remains coated on the portions of the substrate where the first material was not present, thereby defining the boundaries of the thin film structure by comprising a negative image thereof of the thin film structure such that the second material is not present in and the first material has been stripped from the area where the thin film structure is to be formed;

depositing a thin film layer <u>material</u> on the patterned top surface of the substrate; and stripping the second material <u>and the thin film material deposited on the second</u> <u>material</u> to form the thin film structure.

51. (currently amended) The process for forming a patterned thin film structure on a substrate as recited in claim 50, wherein the first material repels the second material such that the second material fills in the areas of the substrate between the areas where the first material has not been printed without coating the areas where the first material is present.

- 52. (currently amended) The process for forming a patterned thin film structure on a substrate as recited in claim 50, wherein the first solvent is an aqueous solution or water.
- 53. (withdrawn and currently amended) The process for forming a patterned thin film structure on a substrate as recited in claim 50, wherein the first solvent is a non-aqueous solvent or solution.
- 54. (currently amended) The process for forming a patterned thin film structure on a substrate as recited in claim 50, wherein the first solvent is an aqueous basic solution, and the step of stripping the second material comprises using a second solvent comprising an aqueous acidic solution, an aqueous neutral solution, or water.
- 55. (currently amended) The process for forming a patterned thin film structure on a substrate as recited in claim 50, wherein the first solvent is an aqueous acidic solution and the step of stripping the second material comprises using a second solvent comprising an aqueous basic solution, an aqueous neutral solution, or water.
- 56. (currently amended) The process for forming a patterned thin film structure on a substrate as recited in claim 50, wherein the first solvent is an aqueous neutral solution or water and the step of stripping the second material comprises using a second solvent comprising an aqueous acidic solution or an aqueous basic solution.

57-66. (cancelled)